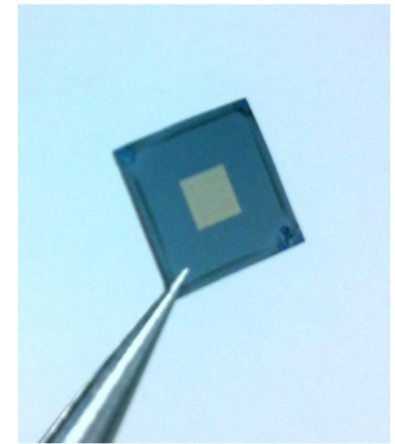
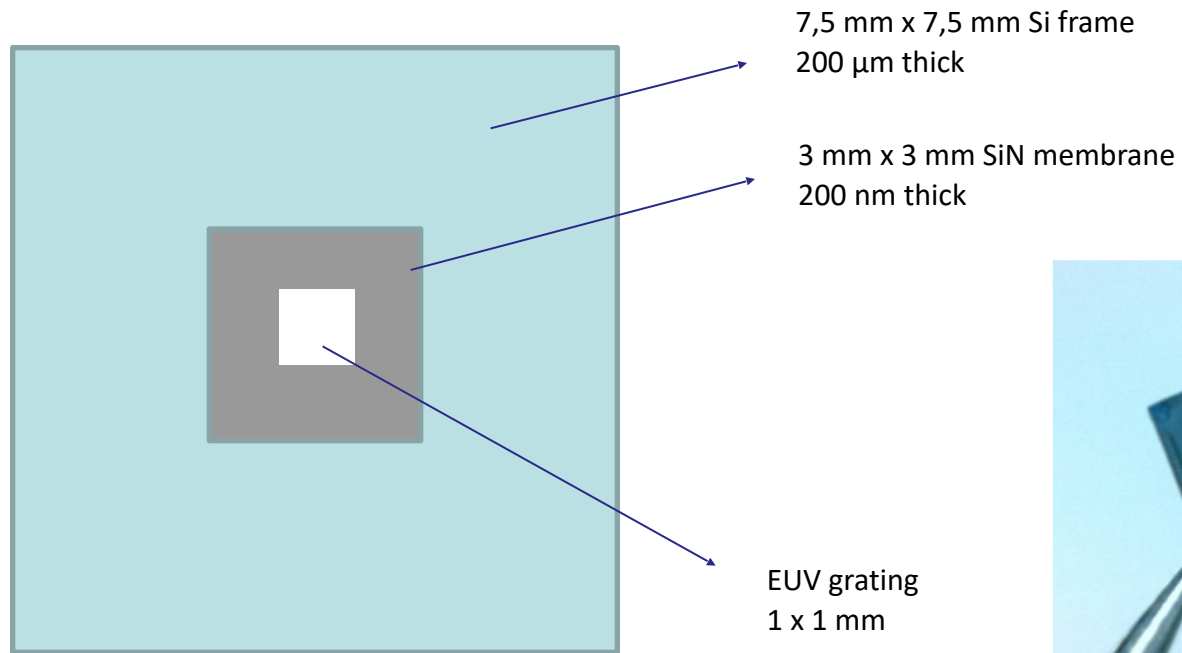
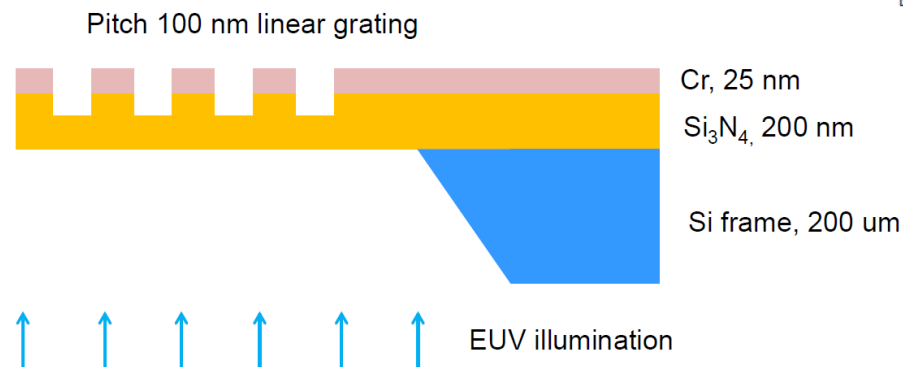


## Top view



EUV grating on silicon nitride membrane

## Cross-section view



\* Not to scale

25 nm open Cr plus 110 nm deep etch into SiN